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Edward W. Reutzel
Editor

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Contents

v	<i>Authors</i>
vii	<i>Conference Committee</i>
ix	<i>The renaissance of CdTe-based photovoltaics (Solar Energy Plenary Paper) [9177-302]</i>
xvii	<i>Hot carrier solar cell absorbers: materials, mechanisms and nanostructures (Solar Energy Plenary Paper) [9178-304]</i>
xxix	<i>International PV QA Task Force's proposed comparative rating system for PV modules (Solar Energy Plenary Paper) [9179-305]</i>

SESSION 1 LASER PROCESSING FOR SOLAR, DISPLAYS, AND OPTOELECTRONICS

9180 02	Overview of laser processing in solar cell fabrication (Invited Paper) [9180-1]
9180 04	Laser processing of glass for consumer electronics: opportunities and challenges (Invited Paper) [9180-3]
9180 05	Laser microprocessing technologies for automotive, flexible electronics, and solar energy sectors (Invited Paper) [9180-4]

SESSION 2 LASER TEXTURING

9180 06	New strategies in laser processing of TCOs for light management improvement in thin-film silicon solar cells (Invited Paper) [9180-8]
9180 07	Influence of surface modification by laser beam interference ablation on characteristics of p-Si solar cells [9180-5]
9180 08	Laser doping of germanium for photodetector applications [9180-6]
9180 09	Formation of periodic structures on silicon by laser beam interference ablation technique for light control in solar cells [9180-7]
9180 0A	Near-field assisted nanoscale patterning for improved absorption in thin film silicon solar cell [9180-22]

SESSION 3 MODELING AND INNOVATIVE TECHNIQUES

9180 0D	Laser processing and in-situ diagnostics for crystallization: from thin films to nanostructures (Invited Paper) [9180-11]
---------	--

- 9180 OF **Sub-bandgap laser annealing of room temperature deposited polycrystalline CdTe**
[9180-13]
- 9180 OH **Silicon PV module customization using laser technology for new BIPV applications** [9180-15]

SESSION 4 PATTERNING AND SCRIBING

- 9180 OI **Selective laser patterning in organic solar cells (Invited Paper)** [9180-16]
- 9180 OK **The effect of film properties and laser processing parameters on the laser ablation of molybdenum thin films** [9180-18]
- 9180 OM **Patterning of OPV modules by ultra-fast laser** [9180-20]

Authors

Numbers in the index correspond to the last two digits of the six-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first four digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

Abramov, Anatoli A., 04	Patterson, Robert, xvii
Abreu Fernandes, S., 0I	Paudel, Naba, 0F
Balenzategui, José Lorenzo, 0H	Prabhathan, P., 0A
Bao, Yiliang, 08	Račiukaitis, G., 07, 09
Bathe, Ravi, 05	Réza, A., 07
Bertomeu, J., 06	Rodrigues, Rafael, 0K
Brabec, Christoph J., 0M	Ryu, Sang-Gil, 0D
Canteli, D., 06	Salleo, Alberto, 0F
Casado, Leonardo, 0H	Sánchez-Aniorte, M. I., 06
Chung, Simon, xvii	Scarpulla, Michael A., 0F
Conibeer, Gavin, xvii	Schneller, Eric, 02, 0K
Dai, Xi, xvii	Selskis, A., 07
del Caño, Teodosio, 0H	Shrestha, Santosh, xvii
Dhere, Neelkanth G., 02, 0K	Sidharthan, R., 0A
Duggal, Anil R., ix	Šimkienė, I., 07, 09
Feng, Yu, xvii	Simonds, Brian J., 0F
Ferekides, Christos, 0F	Smyth, Suntrana, xvii
García-Ballesteros, Juan José, 0H	Spyropolous, George, 0M
Grigoropoulos, Costas P., 0D	Streltsov, Alexander M., 04
Guo, Fei, 0M	Sun, Keye, 08
Gupta, Mool C., 08	Suzanovičienė, R., 09
Gupta, Neeti, xvii	Tayebjee, Murad, xvii
Hernández, S., 06	Valencia, Daniel, 0H
Huang, Shujan, xvii	Vandewal, Koen, 0F
Huber, William H., ix	Voigt, Monika M., 0M
Hwang, David J., 0D	Voisiat, B., 07, 09
In, Jung Bin, 0D	Wang, Pei, xvii
Indrišiūnas, S., 07, 09	Wohlgemuth, John, xxix
Kar, Aravinda, 02, 0K	Xia, Hongze, xvii
Knopf, George K., 05	Xiang, Bin, 0D
Kubiš, Peter, 0M	Yoo, Jae-Hyuck, 0D
Kurtz, Sarah, xxix	Zhang, Pengfei, xvii
Lauzurica, Sara, 06, 0H	Zhang, Zhilong, xvii
Li, Xinghua, 04	Zheng, Andy Cheng, 0D
Liao, Yuanxun, xvii	
Lin, Shu, xvii	
Liu, Anping, 04	
Llusà, M., 06	
López-Vidrier, J., 06	
Lucera, Luca, 0M	
Maragkaki, S., 0I	
Mažeikienė, R., 07	
Minor, Andrew M., 0D	
Misra, Sudhajit, 0F	
Molpeceres, Carlos, 06, 0H	
Morales, Miguel, 0H	
Murukeshan, V. M., 0A	
Nikumb, Suwas, 05	
Ostendorf, A., 0I	

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